

**PATENT**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of: **Hidemasa KAI**

Serial Number: **Not Yet Assigned**

Filed: **July 25, 2003**

**Customer No.: 23850**

For: **EPITAXIAL WAFER PRODUCTION APPARATUS AND SUSCEPTOR  
STRUCTURE**

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents  
P. O. Box 1450  
Alexandria, VA 22313-1450

July 25, 2003

Sir:

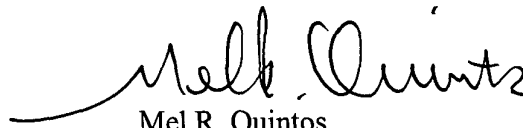
In compliance with 37 CFR 1.56, Applicant calls to the attention of the Patent and Trademark Office the reference listed on the attached PTO-1449.

A copy of the reference is enclosed herewith.

In the event there are any fees due in connection with the filing of this paper, please charge

Deposit Account No. 01-2340.

Respectfully submitted,  
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Enclosures: PTO-1449; References (1)

<b>INFORMATION DISCLOSURE STATEMENT PTO-1449</b>	Atty. Docket No. 030901	Serial No. New Appln.
	Applicant(s): Hidemasa KAI	
	Filing Date: July 25, 2003	Group Art Unit:

### U.S. PATENT DOCUMENTS

Examiner Initial	Document No.	Name	Date	Class	Subclass	Filing Date (If appropriate)
_____	AA					
_____	AB					
_____	AC					
_____	AD					

### FOREIGN PATENT DOCUMENTS

Document No.	Date	Country	Translation (Yes or No)		
_____	AE	10-223545	08/21/98	Japan	Abstract.
_____	AF				
_____	AG				
_____	AH				
_____	AI				

### OTHER DOCUMENTS

_____	AJ			
_____	AK			
<table border="0" style="width: 100%;"> <tr> <td style="width: 50%;">Examiner</td> <td style="width: 50%;">Date Considered</td> </tr> </table>			Examiner	Date Considered
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